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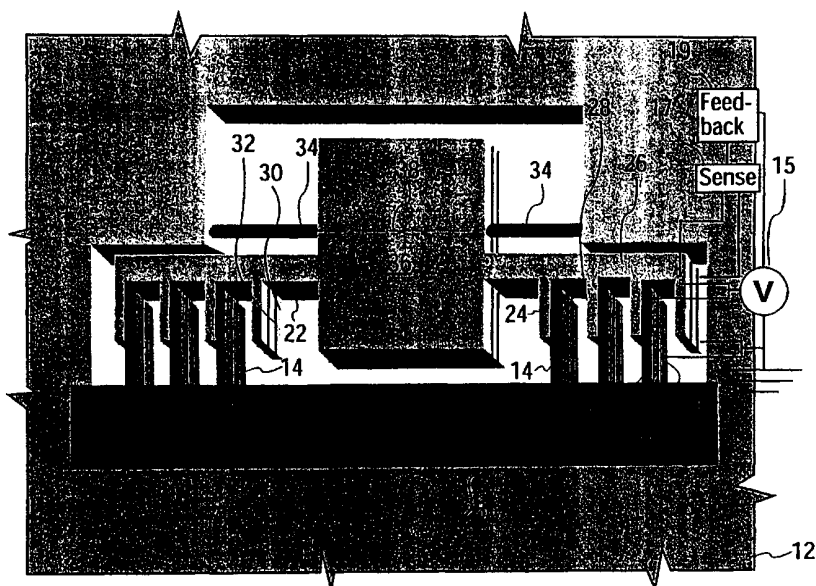
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For two-letter codes and other abbreviations, refer to the "Guidance Notes on Codes and Abbreviations" appearing at the beginning of each regular issue of the PCT Gazette.

(54) Title: MULTI-LAYER, SELF-ALIGNED VERTICAL COMB-DRIVE ELECTROSTATIC ACTUATORS AND FABRICATION METHODS



(57) Abstract: A multi-layer vertical comb-drive actuator includes a first comb structure having a plurality of first comb fingers (14) and a second comb structure having a plurality of second comb fingers (24), wherein the first and second comb fingers are substantially interdigitated. The first and second comb fingers may include two or more stacked conductive layers electrically isolated from each other by an insulating layer or an air gap. Alternatively, either the first or second comb fingers may include only one conductive layer. An application of a voltage (15) between the first and second comb fingers causes the second comb structure to move relative to the first comb structure. The present invention includes a 2D-gimble configuration to rotate a movable element along two axes.

# INTERNATIONAL SEARCH REPORT

International Application No

PCT/US 01/09462

## A. CLASSIFICATION OF SUBJECT MATTER

IPC 7 H02N1/00 B81B3/00 B81B5/00

According to International Patent Classification (IPC) or to both national classification and IPC

## B. FIELDS SEARCHED

Minimum documentation searched (classification system followed by classification symbols)

IPC 7 B81B H02N

Documentation searched other than minimum documentation to the extent that such documents are included in the fields searched

Electronic data base consulted during the international search (name of data base and, where practical, search terms used)

EPO-Internal, WPI Data, PAJ, INSPEC, COMPENDEX

## C. DOCUMENTS CONSIDERED TO BE RELEVANT

Category *	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
X	YAO Z J ET AL: "SINGLE CRYSTAL SILICON SUPPORTED THIN FILM MICROMIRRORS FOR OPTICAL APPLICATIONS" OPTICAL ENGINEERING, SOC. OF PHOTO-OPTICAL INSTRUMENTATION ENGINEERS. BELLINGHAM, US, vol. 36, no. 5, 1 May 1997 (1997-05-01), pages 1408-1413, XP000692372 ISSN: 0091-3286 figures 1,2 paragraph 'FABRICATION!	1,2,4-8, 10-14, 17,18
Y		28-30, 32,35
A		3,9,15, 16, 19-27, 31,33
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Further documents are listed in the continuation of box C.



Patent family members are listed in annex.

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International Application No

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## C.(Continuation) DOCUMENTS CONSIDERED TO BE RELEVANT

Category	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
X	XU Y ET AL: "INTEGRATED MICRO-SCANNING TUNNELING MICROSCOPE" APPLIED PHYSICS LETTERS, AMERICAN INSTITUTE OF PHYSICS. NEW YORK, US, vol. 67, no. 16, 16 October 1995 (1995-10-16), pages 2305-2307, XP000544364 ISSN: 0003-6951 figures 1,2,4 page 2305, column 2, line 9 -page 2307, column 1, line 16	1,2,4,5, 12,13, 15-20, 22-27, 33,34, 36,37
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A		3,6-11, 14,21,31
X	--- SELVAKUMAR A ET AL: "VERTICAL COMB ARRAY MICROACTUATORS" PROCEEDINGS OF THE WORKSHOP ON MICRO ELECTRICAL MECHANICAL SYSTEMS. (MEMS). AMSTERDAM, JAN. 29 - FEB. 2, 1995, NEW YORK, IEEE, US, vol. WORKSHOP 8, 29 January 1995 (1995-01-29), pages 43-48, XP000555241 ISBN: 0-7803-2504-4 figures 1,2,6 paragraph 'FABRICATION!	1,2,4-6, 15,16
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# INTERNATIONAL SEARCH REPORT

Information on patent family members

Int'l Application No

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